THE INVENTION CLAIMED IS:

- A standardized facilities box comprising:
 a box;
- a mechanism for mounting the box to a support

 5 pedestal of a semiconductor fabrication facility; and
 one or more mechanisms for selectively coupling any
 one of a set of add-on features within the box.
- 2. The standardized facilities box of claim 1
 10 further comprising an add-on feature coupled to the one or
 more mechanisms for selectively coupling.
 - 3. The standardized facilities box of claim 2 wherein the add-on feature comprises a partition.
 - 4. The standardized facilities box of claim 2 wherein the add-on feature comprises a document storage compartment.
 - 5. The standardized facilities box of claim 2 wherein the add-on feature comprises a sensor and a warning indicator.
 - 6. The standardized facilities box of claim 2 wherein the add-on feature comprises an automatic lockout mechanism.
- 7. The standardized facilities box of claim 2 wherein the add-on feature comprises a tool storage 30 mechanism.
 - 8. The standardized facilities box of claim 2 wherein the add-on feature comprises a support leg.
- yherein the add-on feature comprises a bridge mechanism adapted to interface between the mechanism for mounting the box and a support pedestal.

- 10. The standardized facilities box of claim 2 wherein the add-on feature comprises a mechanical locating mechanism for a facilities connection.
- 11. The standardized facilities box of claim 2 wherein the add-on feature comprises another standardized facilities box comprising:

a box;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and one or more mechanisms for selectively coupling any one of a set of add-on features to the box.

- 12. The standardized facilities box of claim 2 wherein the add-on feature comprises an openable cover.
- 13. The standardized facilities box of claim 2 wherein the add-on feature comprises floor lighting.
- 14. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower the box into or from a position for mounting the box to a support pedestal.

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- 15. The standardized facilities box of claim 2 wherein the add-on feature comprises a lifting mechanism adapted to lift and/or lower an item to or from the box.
- 30 16. A facilities box comprising:

a box;

a mechanism for mounting the box to a raised floor tile of a semiconductor fabrication facility; and

a support leg coupled to the box for supporting the

35 box.

17. A facilities box comprising:

a box adapted to house facilities connections therein:

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and

a lifting mechanism coupled to the box adapted to lift and/or lower the box into or from a position for mounting the box to a support pedestal.

18. A facilities box comprising:

10 a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and

a lifting mechanism adapted to lift and/or lower an item to or from the box.

19. A facilities box comprising:

a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and a sensor.

20. A facilities box comprising:

a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility; and an exhaust mechanism.

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21. A facilities box comprising:

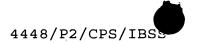
a box adapted to house facilities connections therein;

a mechanism for mounting the box to a support pedestal of a semiconductor fabrication facility;

a cover coupled to the box; and

a lockout mechanism adapted to lock the cover of the box.

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- 22. The facilities box of claim 21 wherein the lockout mechanism is a lockout tag out mechanism.
- 23. A method of standardizing a semiconductor fabrication facility, comprising:

indicating a location within a fabrication facility for installing a facilities box;

providing a standardized facilities box having a mechanism for selectively coupling any one of a set of add-on features to the standardized facilities box;

providing a plurality of add-on features; and specifying which add-on feature should be selectively coupled to which selective coupling mechanism of the standardized facilities box.